



Docket No. 740819-1041

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:)	
Takeshi Yamashita et al.)	Group Art Unit: 1765
Serial No. 10/759,180)	Examiner: Chen, Kin-Chan
Filed: January 20, 2004)	Confirmation No. 7694
For: DRY ETCHING METHOD, FABRICATION METHOD FOR SEMICONDUCTOR DEVICE, AND DRY ETCHING APPARATUS)	Date: March 21, 2006

AMENDMENT

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Office Action mailed December 22, 2005, to the Examiner interview conducted March 2, 2006 and to a telephonic conference with the Examiner on the same date, and please amend the above identified application and consider Applicants' remarks as follows.